

Ion-plasma spraying unit NIKA-148



Vacuum ion-plasma spraying unit Nika 2012-500-148 is designed for the deposition of metal-film coatings on dielectric substrates of various configurations, thickness:
titanium - (0.5-30) microns;
molybdenum - (0.1-5) microns.

The vacuum chamber of the installation is equipped with:

- two electric arc evaporators;
- heater;
- radio frequency plasma generator RFPG-128 (RPG);
- a damper for overlapping EDI;
- carousel with media rotation with substrates (12 pcs.);
- vacuum input of the carousel rotation;
- infrared pyrometer Optis CTlaser 3MH-SF-CB3.

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Layout and characteristics



Heater L200



**RPG-128 (RPG) -
radio frequency
plasma generator**

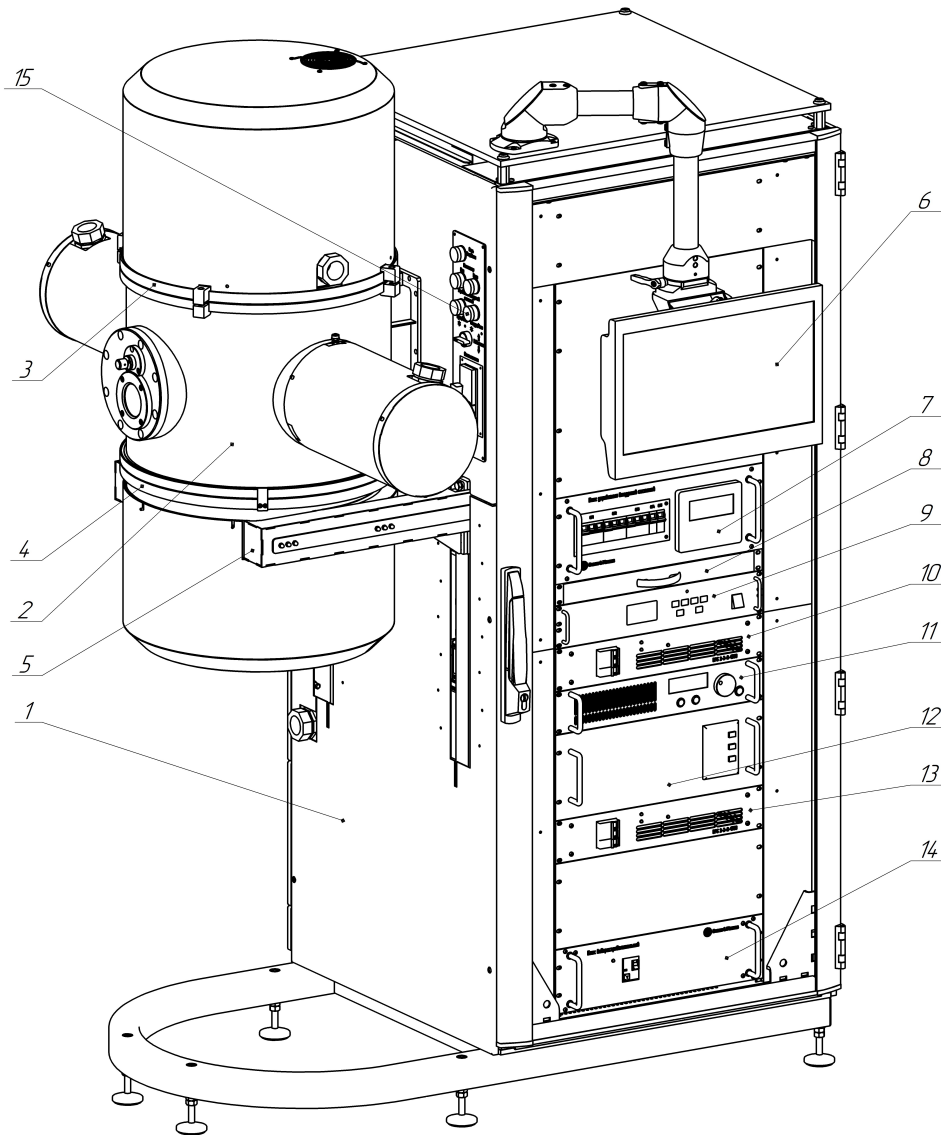


**Electric arc
evaporator - 2
pcs.**

Power	24 kW
Maximum power consumption	no more than 8 kW
Supply voltage	380 V (+ 10-15)%
Connection	TN-S
Maximum current consumption on phases	32A
Weight (excluding OWL, foreline pump)	no more than 750 kg
Ultimate vacuum	no more than 7 10 ⁻⁵ Pa
Time to reach ultimate vacuum (from the moment the shutter is opened)	no more than 30 min
Maximum working temperature	
Heat treatment of substrates after spraying	350 °C
Holding time during heat treatment	120 min
Working gases	argon, nitrogen
Number of gas injection channels	2
Coolant	(recommended) distilled water, 20% ethyl alcohol solution in distilled water
Coolant volume	15 l
Cooling liquid consumption	no more than 15 l / min

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Components



- 1 - frame;
- 2 - vacuum chamber;
- 3 - upper flange;
- 4 - bottom flange;
- 5 - lifting frame;
- 6 - monitor;
- 7 - vacuum system control unit;
- 8 - shelf with keyboard and mouse;
- 9 - controller TMH TCDP-II;
- 10 - heater power supply unit;
- 11 - HF generator GA-13.1.A7;
- 12 - power supply for the arc evaporator IPD-70-2.0;
- 13 - bias potential power supply unit BPS 2-3-2-1500;
- 14 - water distribution block.
- 15 - control panel.

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